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	APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR		ATTORNEY DOCKET NO.	
	08/958,460	10/28/97	LIU		C	UMC-96-279
Γ	-		· IM62/0819	·		EXAMINER
	LAW+		1002/001	.7	SERGE	ENT,R
	993 HIGHLANDS CIRCLE				ART UNIT	PAPER NUMBER
	LOS ALTOS	CA 94024			1711	5
					DATE MAILED:	08/19/99

Please find below and/or attached an Office communication concerning this application or proceeding.

Commissioner of Patents and Trademarks

	Application No.	Applicant(s)						
Office Action Summary	08/958,460	Sergent						
Office Action Summary	Examiner	Group Art Unit						
	Sergent	Sergent Group Art Unit						
-The MAILING DATE of this communication appears on the cover sheet beneath the correspondence address-								
Period for Response								
A SHORTENED STATUTORY PERIOD FOR RESPONSE IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.								
- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a response be timely filed after SIX (6) MONTHS from the mailing date of this communication. - If the period for response specified above is less than thirty (30) days, a response within the statutory minimum of thirty (30) days will be considered timely. - If NO period for response is specified above, such period shall, by default, expire SIX (6) MONTHS from the mailing date of this communication. - Failure to respond within the set or extended period for response will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).								
Status								
☐ Responsive to communication(s) filed on								
☐ This action is FINAL.								
 Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 1 1; 453 O.G. 213. 								
Disposition of Claims								
X Claim(s) 1-20		is/are pending in the application.						
Of the above claim(s)	is/are withdrawn from consideration.							
☐ Claim(s)	is/are allowed.							
X Claim(s) 1 - 2 0	is/are rejected.							
□ Claim(s)		is/are objected to.						
☐ Claim(s)								
Application Papers requirement.								
See the attached Notice of Draftsperson's Patent Drawing Review, PTO-948.								
☐ The proposed drawing correction, filed on is ☐ approved ☐ disapproved.								
☐ The drawing(s) filed on is/are objected to by the Examiner.								
☐ The specification is objected to by the Examiner.								
☐ The oath or declaration is objected to by the Examiner.								
Priority under 35 U.S.C. § 119 (a)-(d)								
 □ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 11 9(a)-(d). □ All □ Some* □ None of the CERTIFIED copies of the priority documents have been □ received. □ received in Application No. (Series Code/Serial Number) □ received in this national stage application from the International Bureau (PCT Rule 1 7.2(a)). 								
*Certified copies not received:								
Attachment(s)	(A)							
☐ Information Disclosure Statement(s), PTO-1449, Paper No(s). 2 □ In	nterview Summary, PTO-413						
Notice of References Cited, PTO-892		☐ Notice of Informal Patent Application, PTO-152						
Notice of Draftsperson's Patent Drawing Review, PTO-948		Other						
Office Action Summary								

U. S. Patent and Trademark Office PTO-326 (Rev. 3-97) Art Unit: 1711

1. Claim 2 is rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

It is unclear how the use of "primarily" is intended to further limit the claim.

2. Claims 1,2 and 5-8 are rejected under 35 U.S.C. 112, first paragraph, because the specification, while being enabling for methods wherein high density plasma chemical vapor deposition is used to deposit the dielectric material within the gaps between the wiring lines, does not reasonably provide enablement for methods utilizing other deposition techniques to deposit the dielectric material. The specification does not enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to use the invention commensurate in scope with these claims.

Applicants have provided adequate enablement only for processes utilizing high density plasma chemical vapor deposition, and the position is taken that the claims should be limited in accordance with the teachings of the specification.

3. Claims 1-19 are rejected under 35 U.S.C. 112, first paragraph, as containing subject matter which was not described

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in the specification in such a way as to enable one skilled in the art to which it pertains, or with which it is most nearly connected, to make and/or use the invention.

It is unclear how the antireflective coatings (claim 1) and cap layer (claim 9) and layers directly beneath them are selectively etched. Applicants' claims fail to recite a mask or photoresist layer.

Quality 1-8 and 20 are rejected under 35 U.S.C. 112, first paragraph, because the specification, while being enabling for methods wherein the gaps are filled with dielectric material by the step of high density plasma chemical vapor deposition, does not reasonably provide enablement for methods wherein the deposition step fails to fill the gaps. The specification does not enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to use the invention commensurate in scope with these claims.

The deposition steps of claims 1 and 20 do not specifically require that the dielectric material fill the gaps; however, this is a central objective of applicants' application.

Any inquiry concerning this communication should be directed to R. Sergent at telephone number (703) 308-2982.

RABON SERGENT PRIMARY EXAMINER